



Pro amiti  
R14/C  
C. P.  
6/15/04

In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS,  
ELECTRON BEAM LITHOGRAPHY  
APPARATUS, EXPOSURE APPARATUS,  
EXPOSURE APPARATUS MAINTENANCE  
METHOD, SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD, AND SEMI-  
CONDUCTOR MANUFACTURING FACTORY

Examiner: P. L. Rodriguez

Group Art Unit: 2125

Confirmation No.: 4154

June 2, 2004

RECEIVED

JUN 07 2004

Technology Center 2100

## Mail Stop RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

## PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: